

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		09/853,870	CHAPARALA, MURALI	
Examiner		Art Unit		Page 1 of 1
Omar Rojas		2874		

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,528,887	03-2003	Daneman et al.	257/774
	B	US-5,629,918	05-1997	Ho et al.	310/40MM
X	C	US-6,356,741	03-2002	Bilotti et al.	455/90
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Eyre et al. MEMS Magnetic Sensor in Standard CMOS, Science Closure and Enabling Technologies for Constellation Class [online], [retrieved on 2003-03-17]. Retrieved from the Internet <URL: http://sprg.ssl.berkeley.edu/ConstellationClassMissions/eyre.pdf >
	V	Miller R. et al., A Magnetically Actuated MEMS Scanning Mirror, International Society for Optical Engineering, Vol. 2687 (March 1996), pp. 47-52.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.